

# Ongoing Pixel developments: A very partial summary

# LHC

- We can identify 3 different regions to match radiation damage and occupancy in the current LHC detector

R	$\Phi$	Technology
>50 cm	$10^{13}$	p-on-n strip 500 $\mu\text{m}$ thick, high resistivity ( $\approx 5 \text{ K}\Omega\cdot\text{cm}$ ), pitch $\sim 200 \mu\text{m}$
20-50 cm	$10^{14}$	p-on-n strips 320 $\mu\text{m}$ thick, low resistivity ( $\approx 2 \text{ K}\Omega\cdot\text{cm}$ ), pitch $\sim 80 \mu\text{m}$
<20 cm	$10^{15}$	n-on-n pixels 270 $\mu\text{m}$ thick sensors low resistivity ( $\approx 2 \text{ K}\Omega\cdot\text{cm}$ ) oxygenated

# SLHC

- Radiation fluence increases by about a factor of 10 from one region to the other and by a factor of 10 between LHC and SLHC.

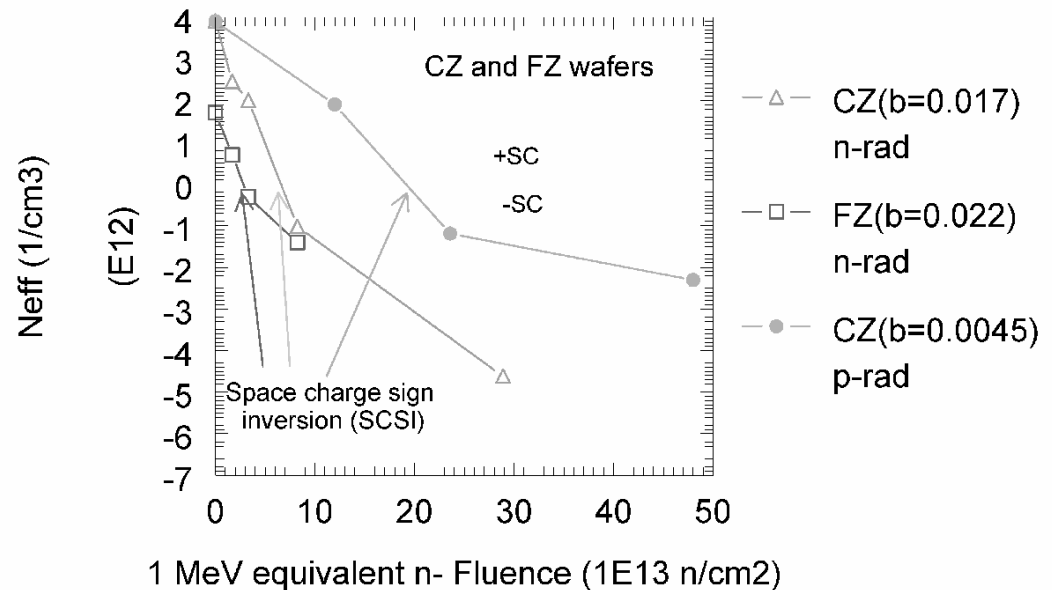
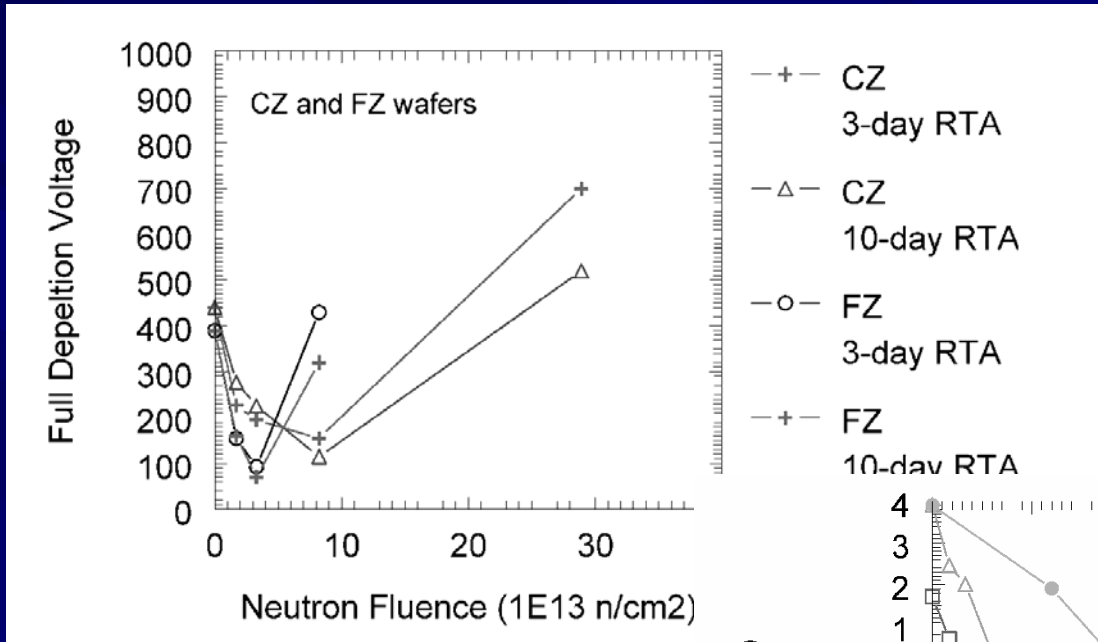
R	$\Phi$	CCE	Technology
>50 cm	$10^{14}$	20ke	Present rad-hard technology (or n-on-p)
20-50 cm	$10^{15}$	10ke	Present n+-n LHC pixel (or n-on-p)
<20 cm	$10^{16}$	>5Ke	RD needed

# Pixel R&D is complex

- Complicated ROC
- Few groups have in house bump-bonding facilities (PSI and UC-Davis)
- Bump Bonding vendors are costly
- Current activities are very detector dependent
- A lot of pixel developments for LC: DEPFETs, MAPS, FAPS etc....

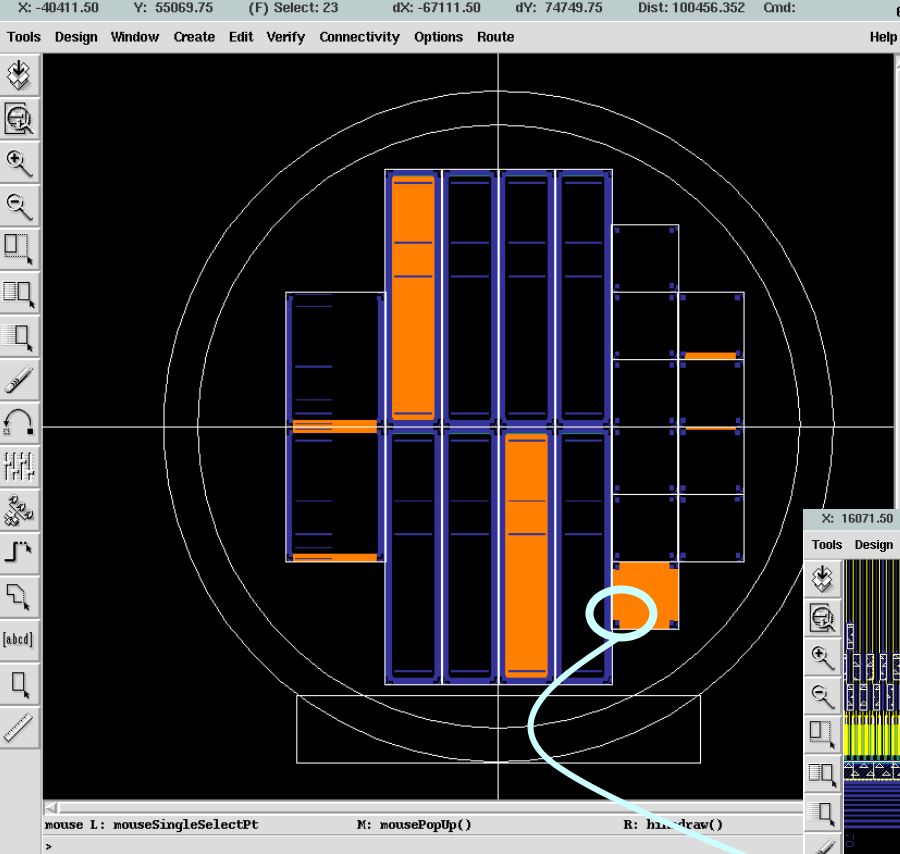
# MCz silicon

■ MCz promises to be more rad hard than FZ



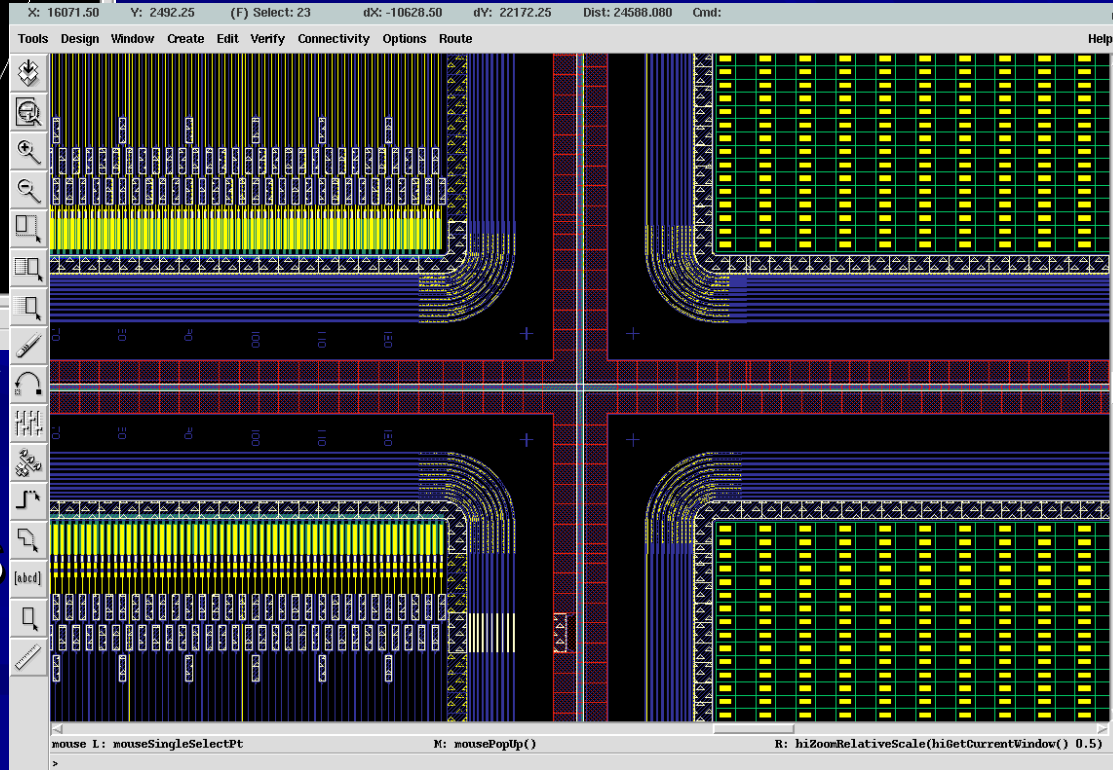
# MCz and thin sensors

- Purdue is processing 5 MCz wafers (thanks to M. Moll and Jaakko) with Sintef using CMS/ FPix masks.
  - Allows easy comparison of FZ, DOFZ and MCz.
  - Sensors have standard CMS FPix design
- Purdue, Rochester and BNL are processing MCz wafers containing pixel and strip sensors at BNL. Some of the strip sensors have the CDF-L00 layout
- Purdue is processing thin wafers with Micron (150  $\mu\text{m}$  -200  $\mu\text{m}$  )



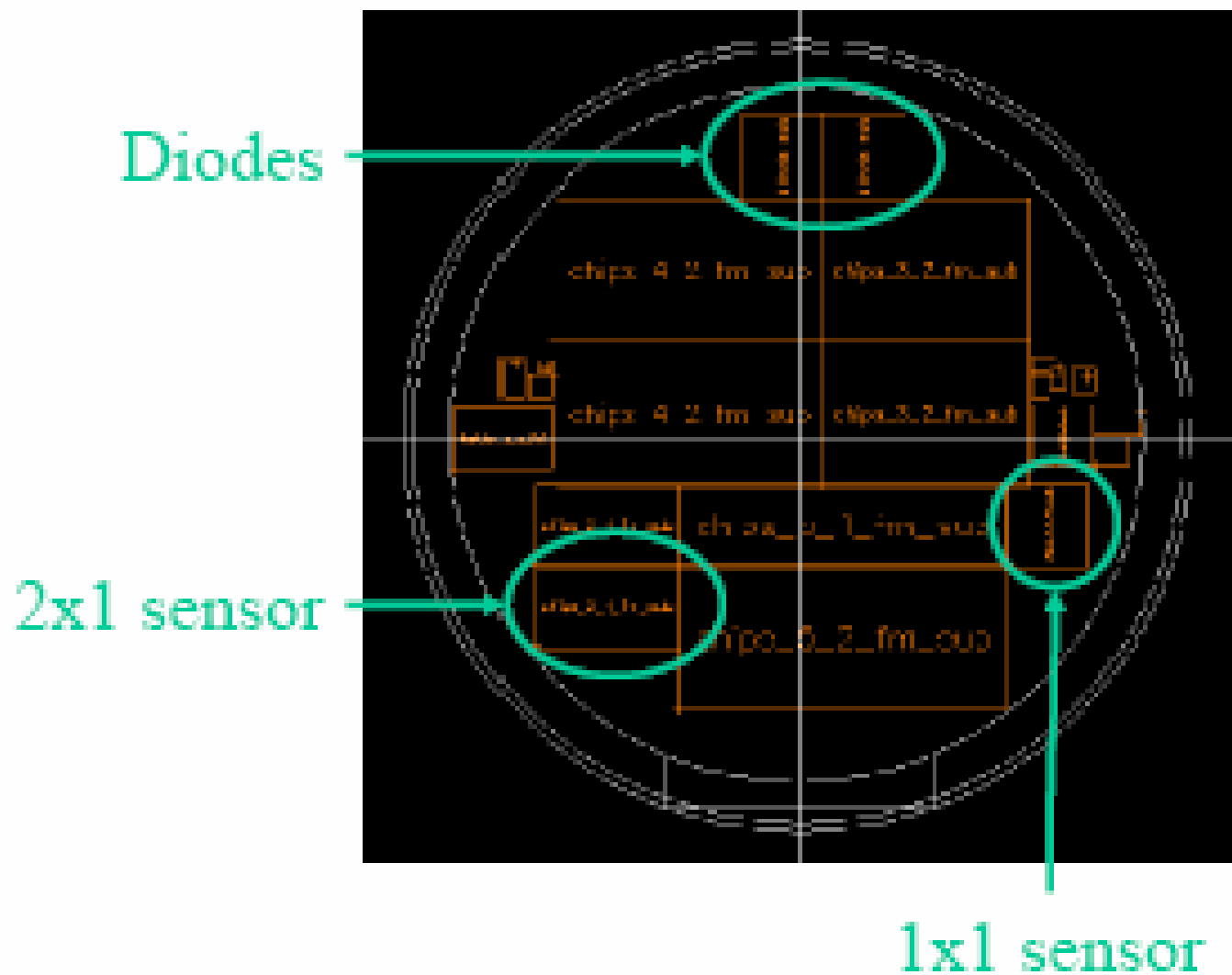
# BNL wafer

Designed  
by G. Bolla



■ Mask design in process. Detectors available in about 6 months

# SINTEF wafer



**Detectors  
delivery  
expected on  
September 1**

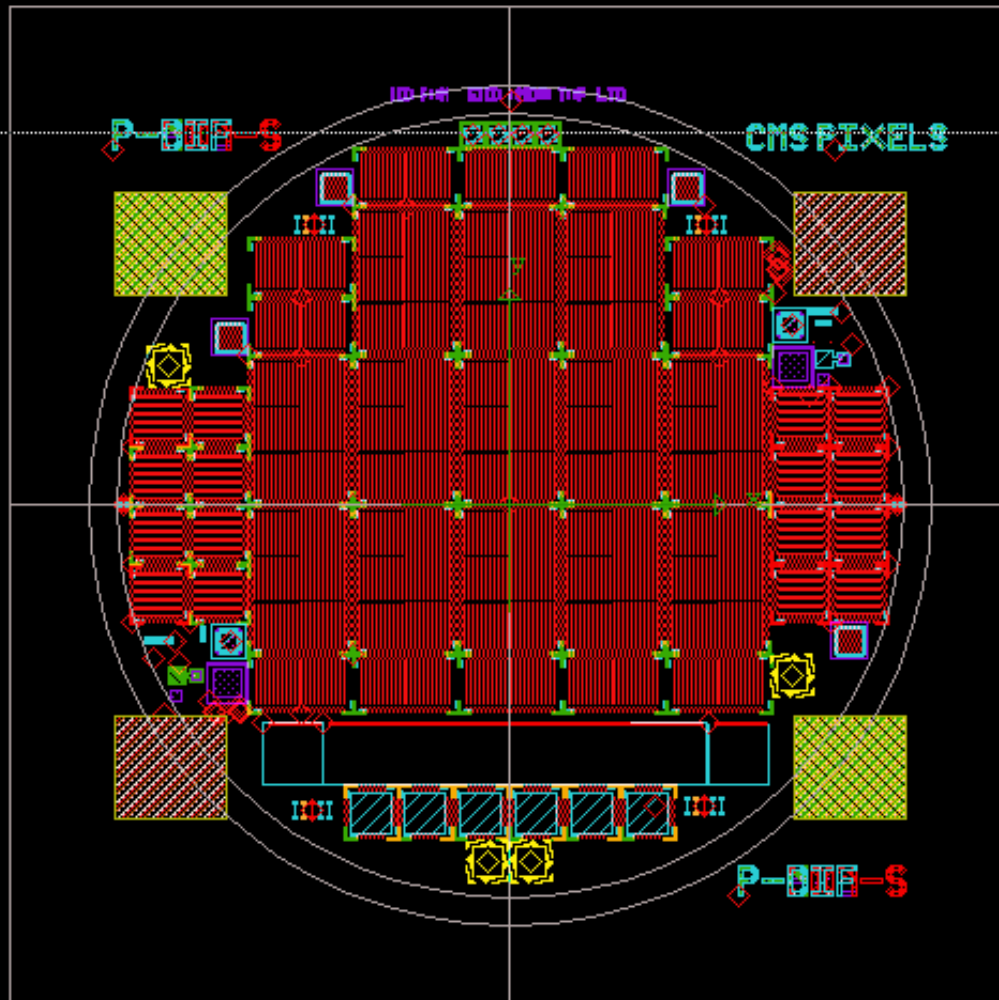
# Thin silicon R&D

- We have received thin silicon strips sensors (fabricated with CDF-L00 masks)
- We will compare: 150, 200 and 300  $\mu\text{m}$  thick strip detectors
  - DC measurements
  - Performance studies using the SVX4 chip developed for the so called "run 2b " of the Tevatron
- Pixel masks have been designed. Each 6" wafer will contain:
  - Several pixels sensors matching the CMS  $\frac{1}{4}$  micron chip (100  $\mu\text{m} \times 150 \mu\text{m}$ ) developed by PSI
  - RD50 PAD structures for SLHC
  - Test structures to study bump bonding
- Pixel sensors should be available for first tests in about 1 month.

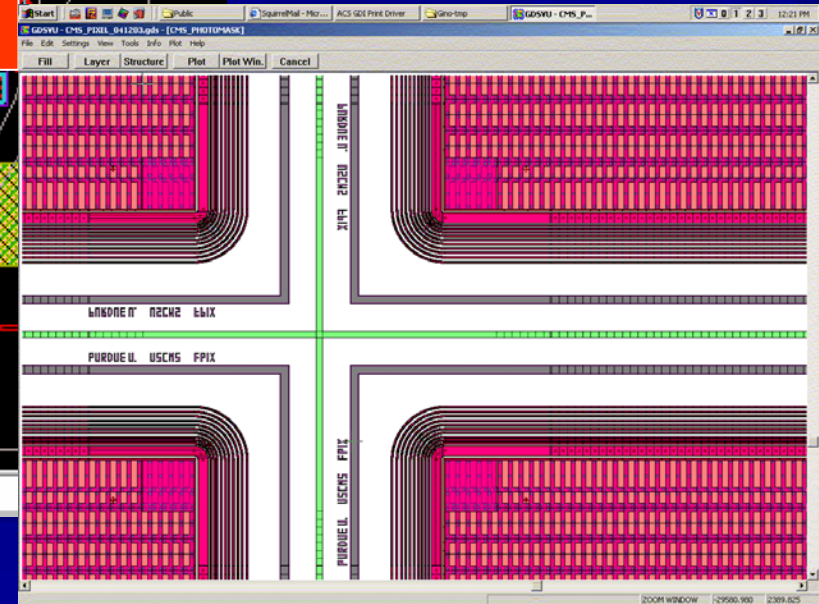
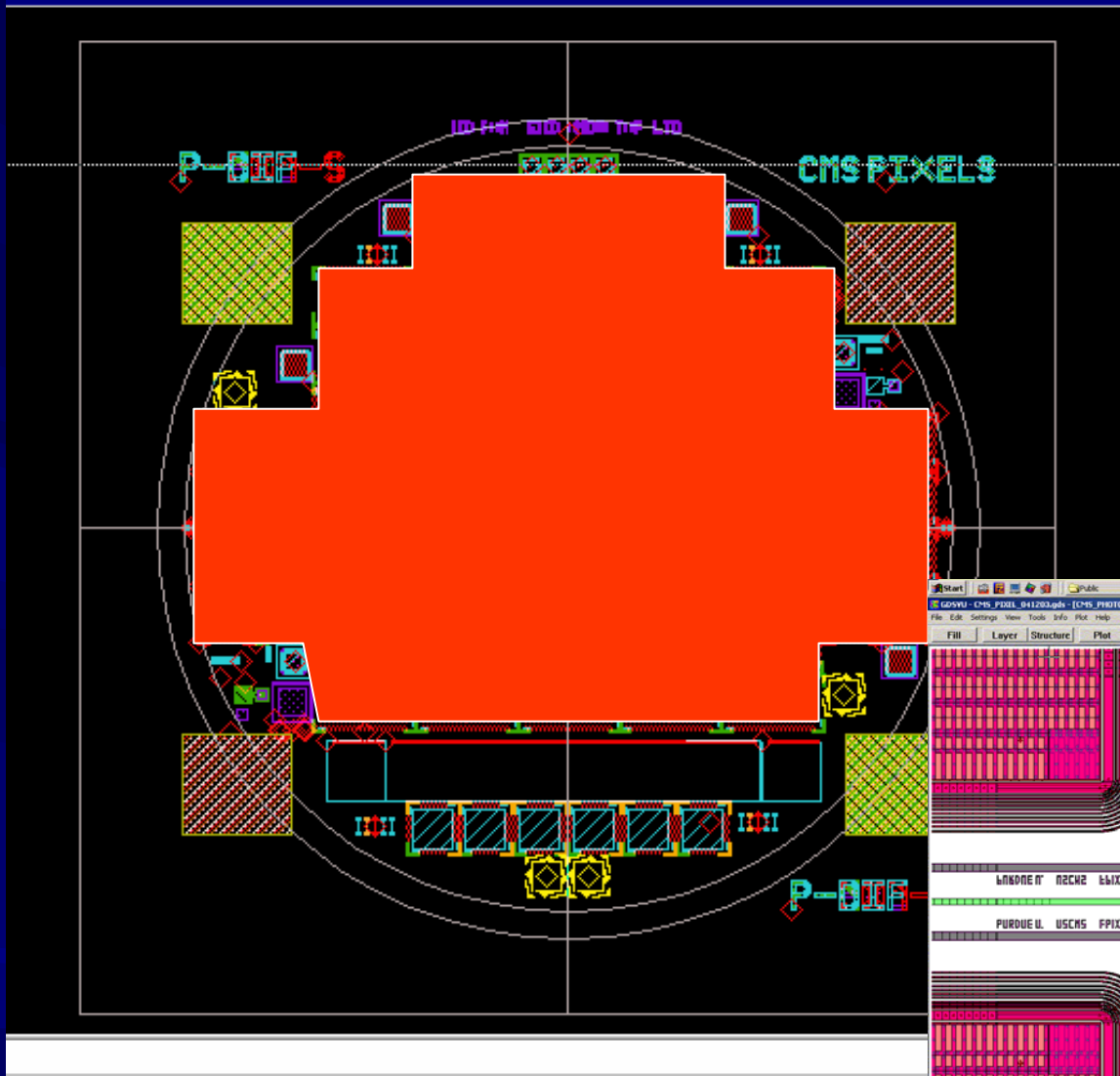


# Thin Pixel Mask Layout

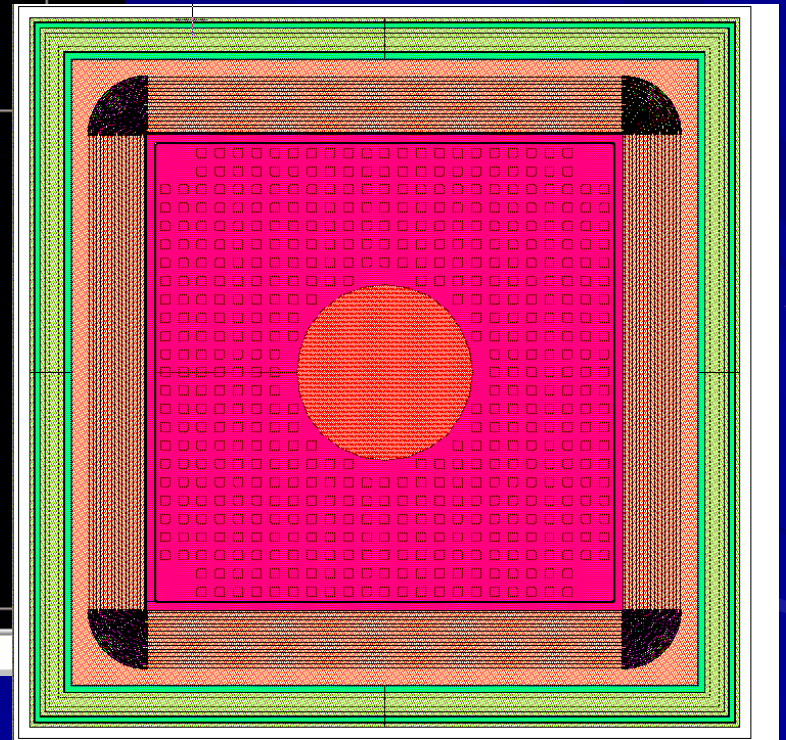
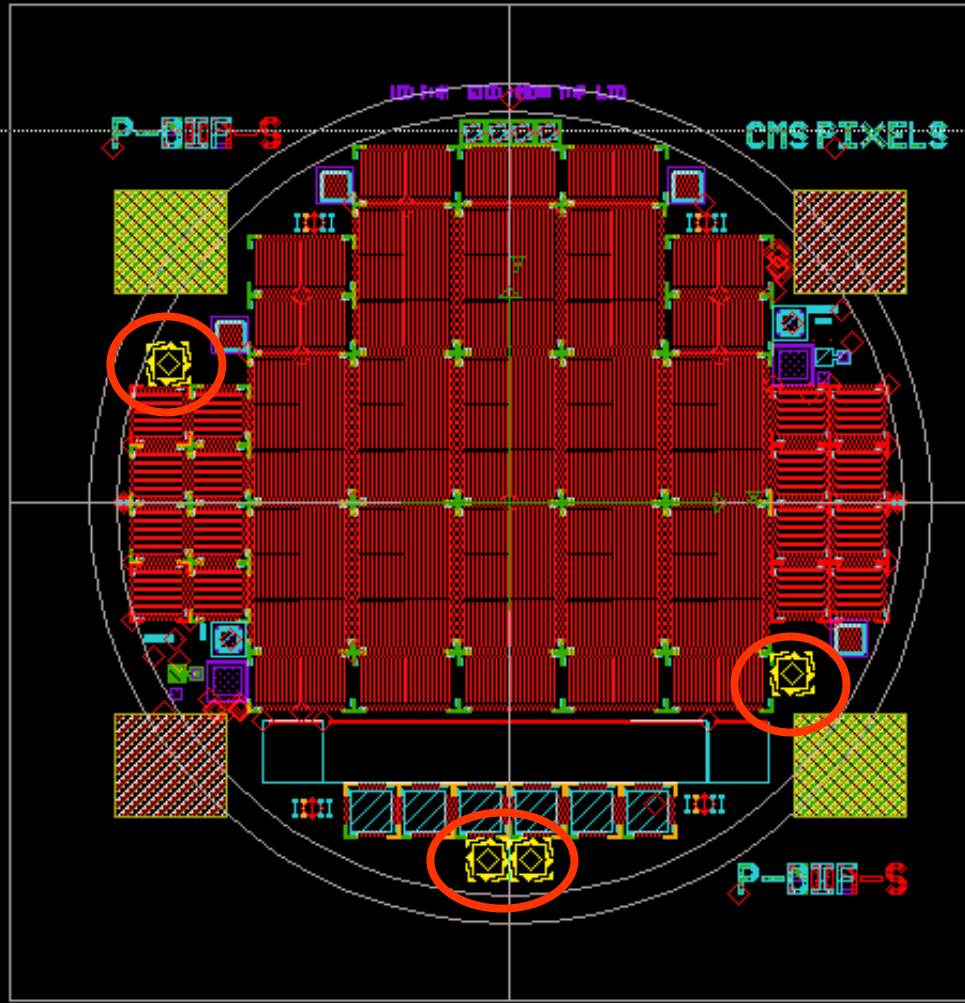
- Masks (6") are fabricated and processing (oxygenation) started in January.
- Devices should be available in ~ 1 month



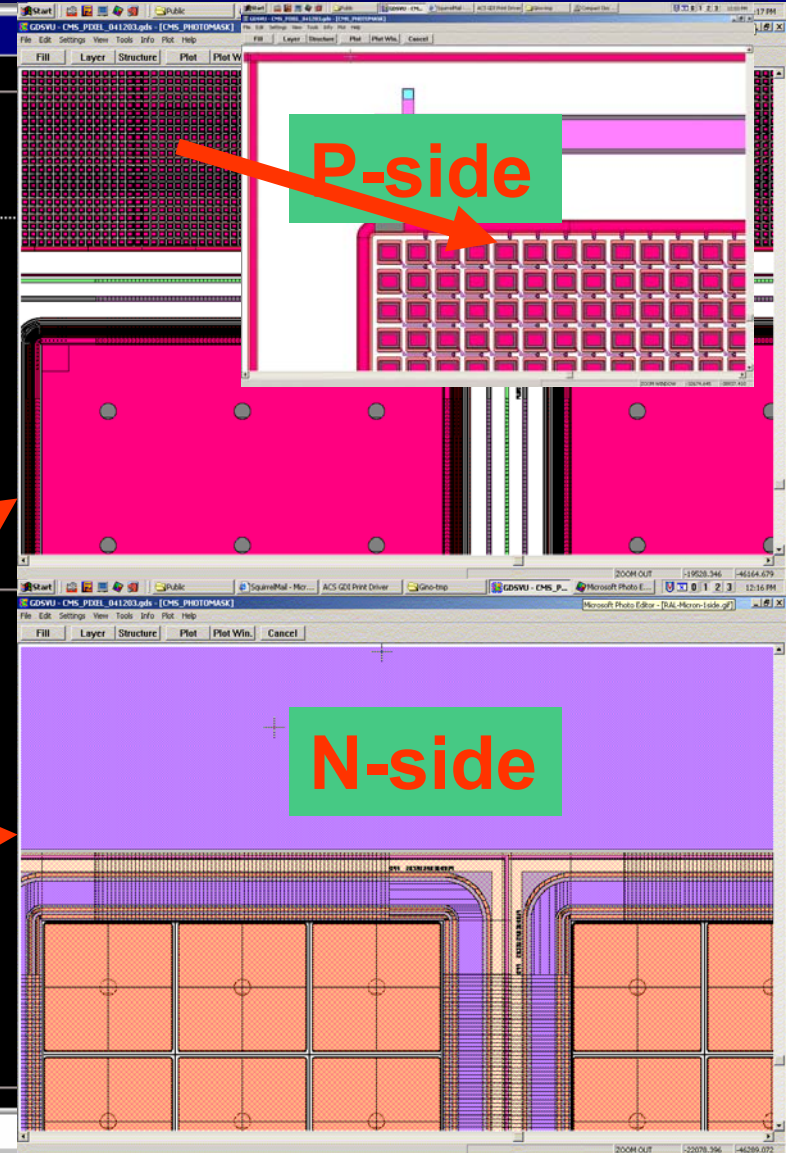
Area is dominated by CMS pixel devices compatible with the 0.25  $\mu\text{m}$  chip



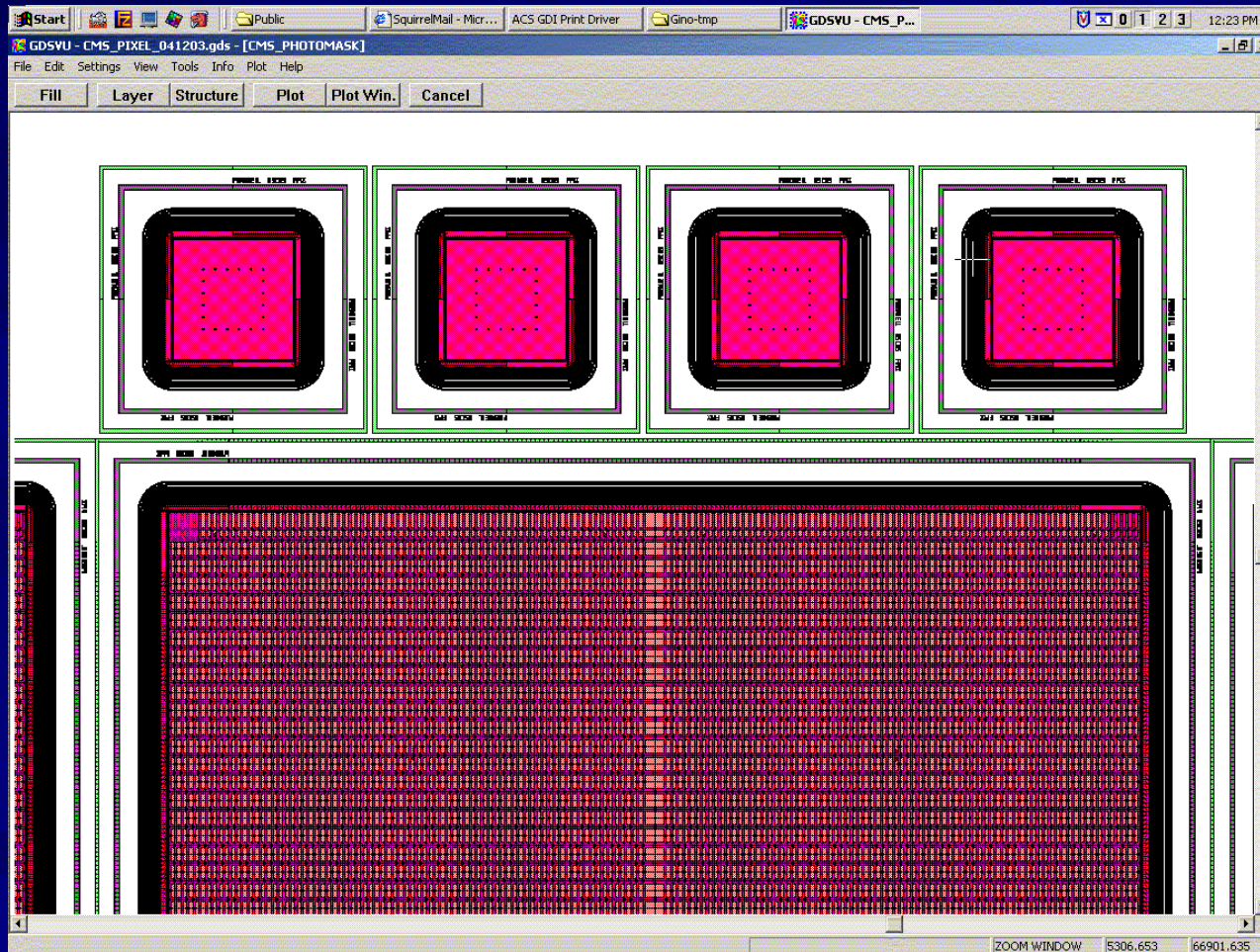
Circled in red  
the RD50  
structures  
(diodes)



**RAL p-on-n pixels  
&  
Micron n-on-p pad  
detectors**



# As usual diodes and other test structure for process control



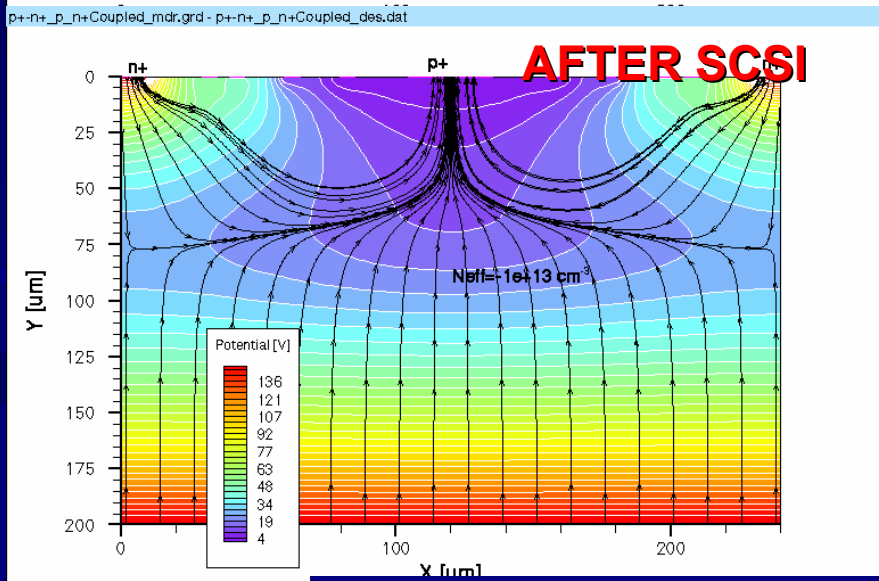
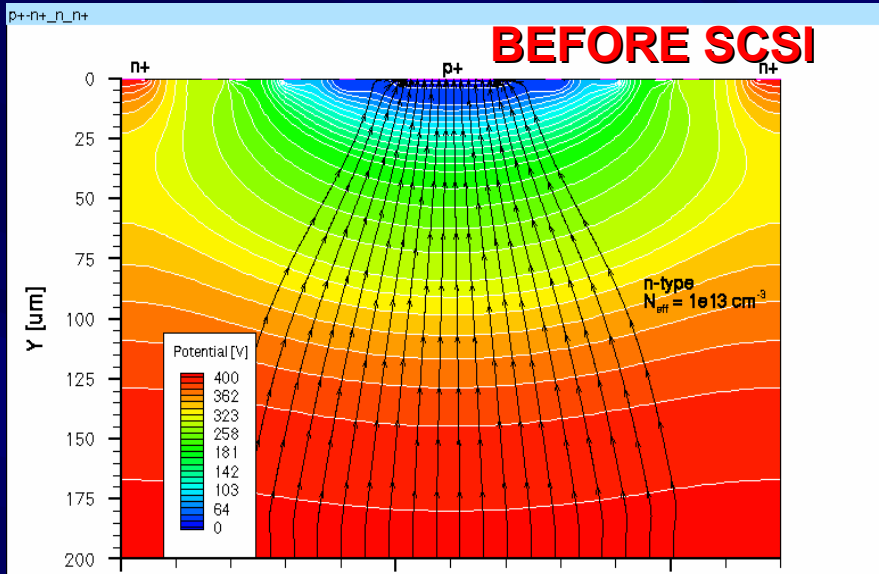
# Other activities

- S. Parker is fabricating pixel sensors for several projects
  - planar/3D active edge for NIH protein crystallography project
  - full 3D active edge for Atlas beam test.
  - TOTEM beam test and high-speed pulse tests with the CERN fast 0.13 micron transimpedance amplifier (Anelli, Jarron, et al.) use full 3D active edge sensors connected to strip readout.

# Other activities

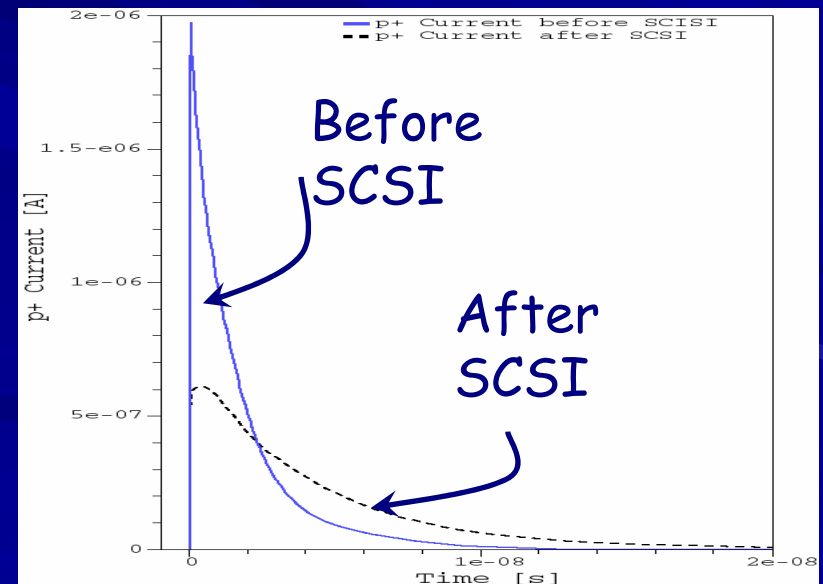
- Several groups are performing pixel simulation:
  - Syracuse, Purdue and JHU (see M. Swartz talk)
  - Uni Zurich (M. Chioggia), PSI, Milan (see T. Lari's talk)
- Aim at comparison between simulation of charge collection properties of different technologies at various irradiation level with experimental data.
  - **Syracuse: BTeV R&D project**
  - **JHU and Purdue: CMS**

# Simulation p+- n+ /n /n+



## Use ISE-TCAD

- Before irradiation:  $N_{\text{eff}} = 10^{13} \text{ cm}^{-3}$ 
  - $V_{\text{fd}} = 400 \text{ V}$ , CCE ~ 98%
- After radiation:  $N_{\text{eff}} = -1 \times 10^{13} / \text{cm}^3$  ( $\phi = 5 \times 10^{14} \text{ n/cm}^2$ )
  - $V_{\text{fd}} = 150 \text{ V}$ , CCE: 91 %
  - Larger fluence  $\Rightarrow$  increase of collection time.



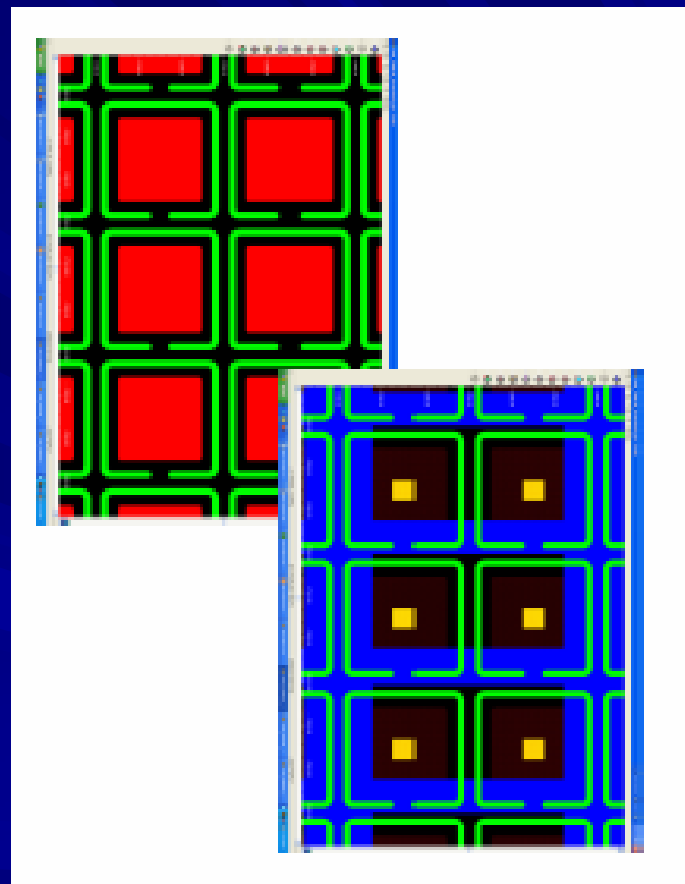


# CCE measurements

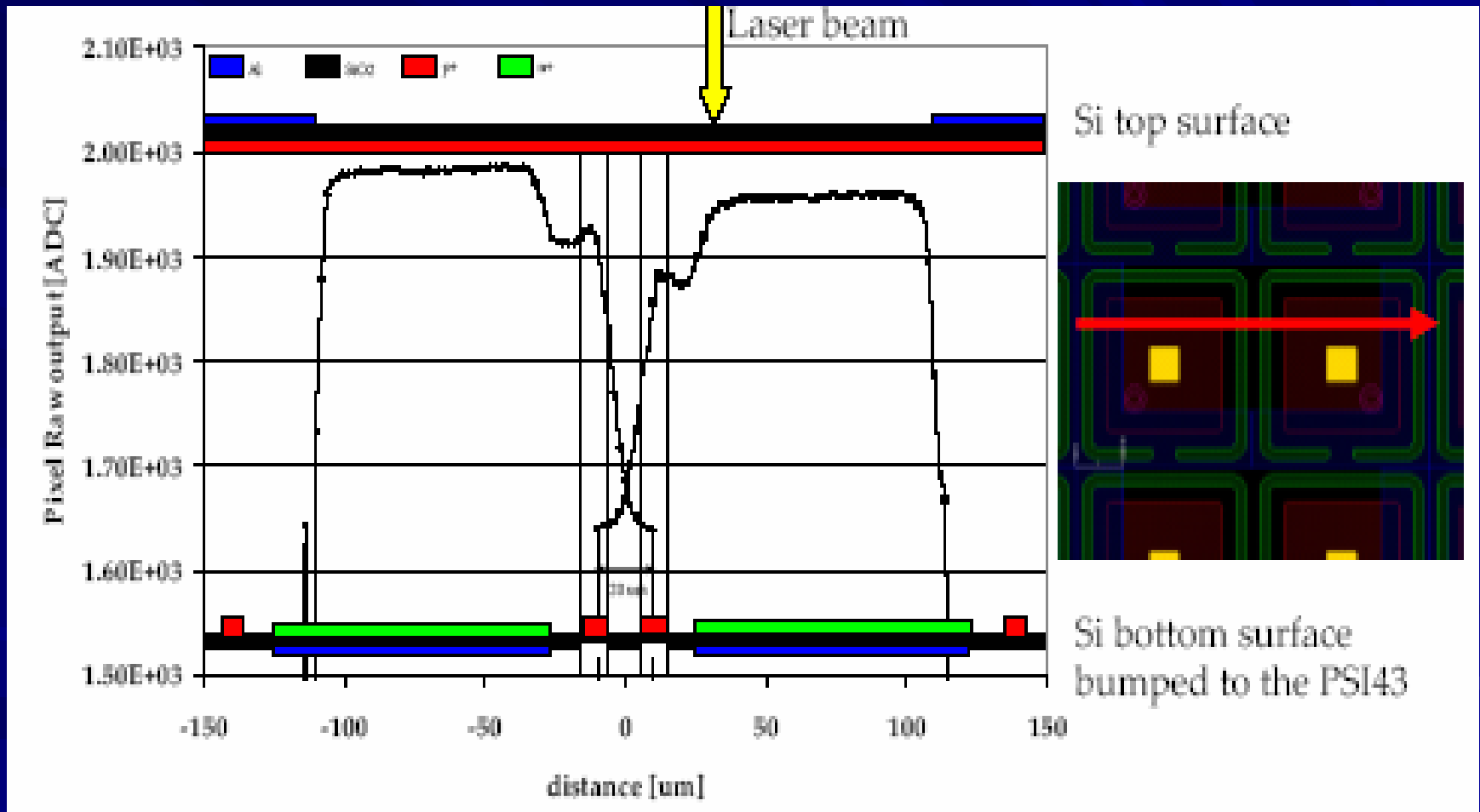
- Beam test area is now working at Fermilab.
- Laser measurements at Purdue and Fermilab
  - Use 1064 nm laser to study the CCE of pixel systems
  - Beam size about 10  $\mu\text{m}$

# Sensor Geometry

- Implanted n+-pixel (metalized)~98%
- P-stops rings 8 $\mu$ m wide with 12  $\mu$ m gaps
- Metal grid on the p-side
- Contact between the Al and n+ pixels



# Laser Scan



# Design and test of innovative CMOS pixel detectors

D. Passeri<sup>(1, 2)</sup>, P. Placidi<sup>(1, 2)</sup>, M. Petasecca<sup>(1, 2)</sup>,  
P. Ciampolini<sup>(1,3)</sup>, G. Matrella<sup>(1, 3)</sup>, A. Marras<sup>(3)</sup>, G.M.  
Bilei<sup>(1)</sup>



(1) Istituto Nazionale di Fisica Nucleare  
Sezione di Perugia - Italy

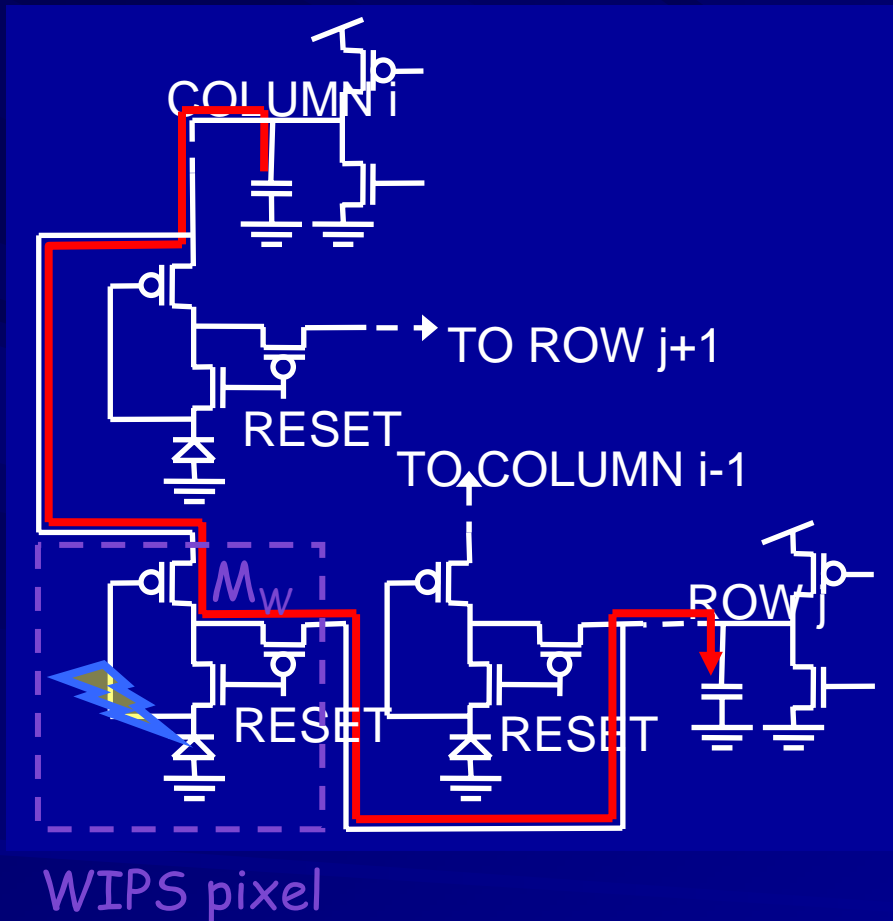


(2) Dipartimento di Ingegneria Elettronica e dell'Informazione  
Università degli Studi di Perugia - Italy



(3) Dipartimento di Ingegneria dell'Informazione  
Università di Parma - Italy

# WIPS architecture

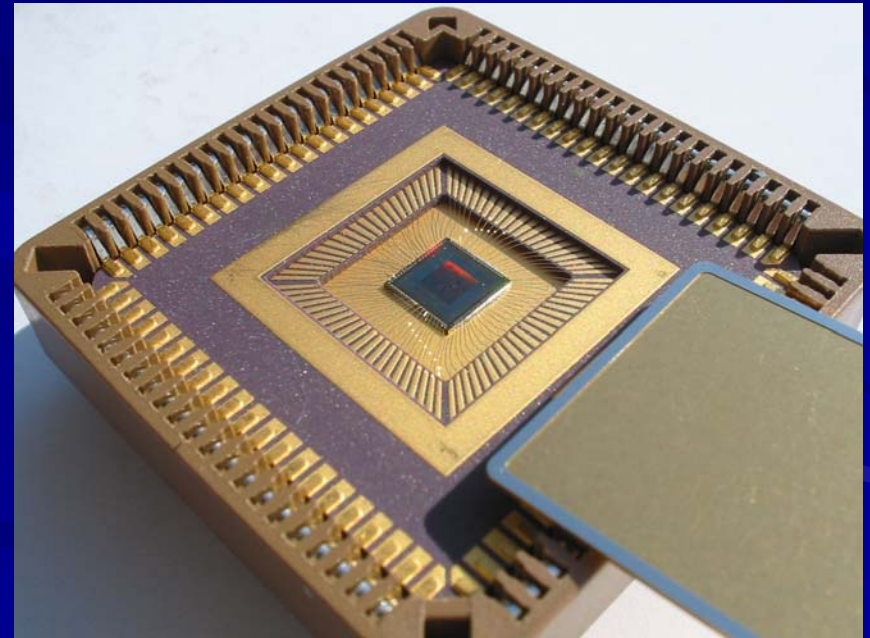
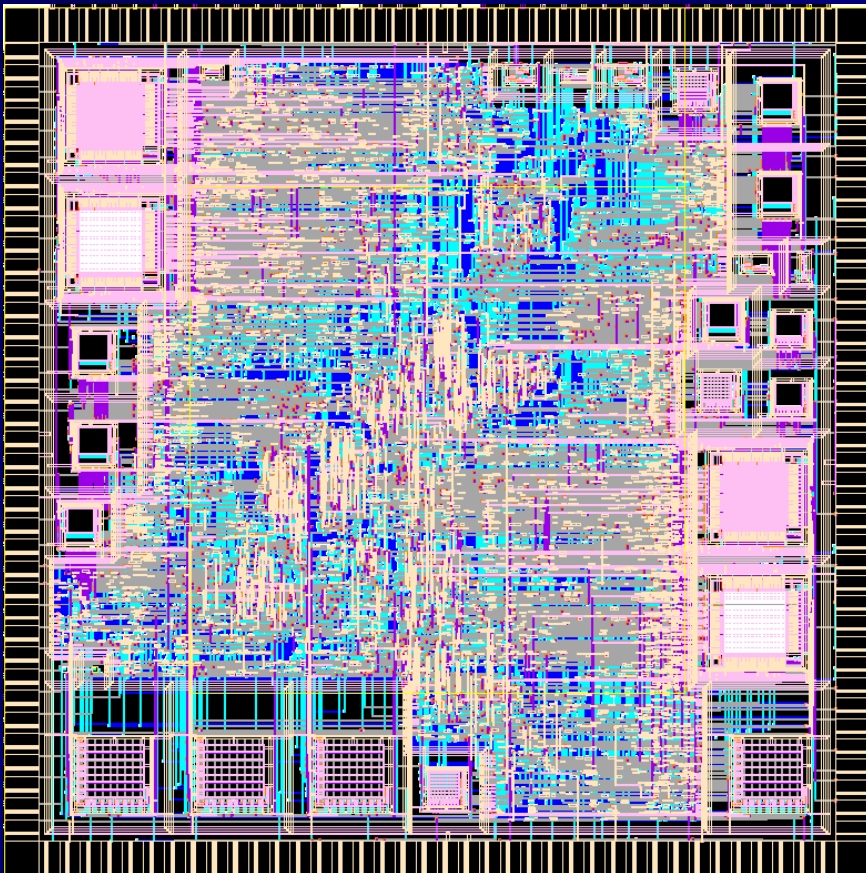


- Pixel architecture 2 PMOS 1NMOS + N-well Diode
- Internal gain  $\sim 10$
- WIPS = Weak Inversion P-MOS
- Pixel area  $10 \mu\text{m} \times \mu\text{m}$
- Dead Area 15%
- Signal = 70-80 mV/MIPS
- $\Delta T(\text{readout}) = 2N_{\text{CLK}}$
- $N_{\text{CLK}} \sim 10 \text{ MHz}$

# RAPS01 chip

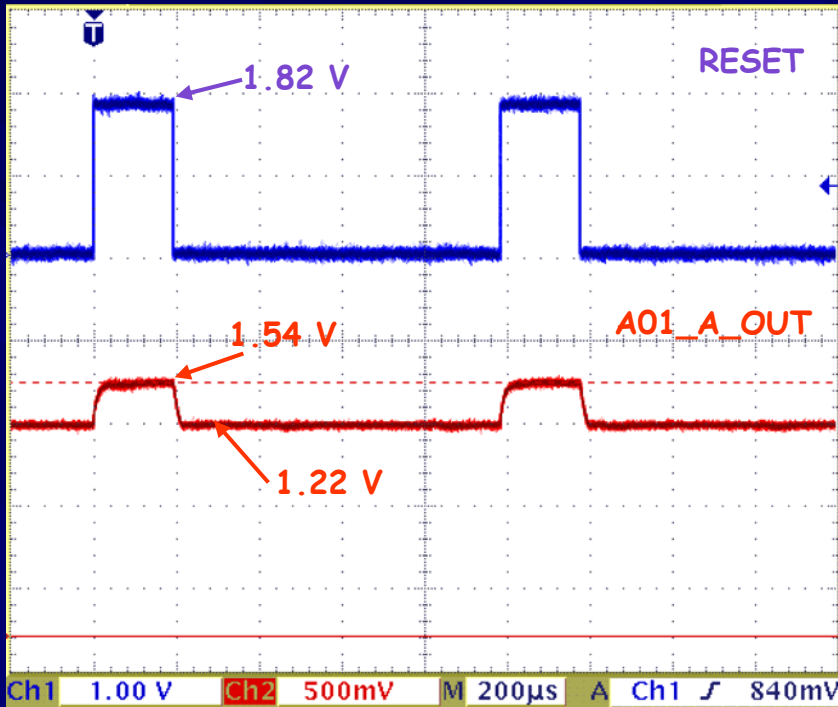
Designed and fabricated in a commercial 0.18  $\mu\text{m}$  CMOS technology

- 11 APS arrays
- 8 WIPS arrays
- test structures
- open-lid, JLCC84 case
- 2 bonding schemes

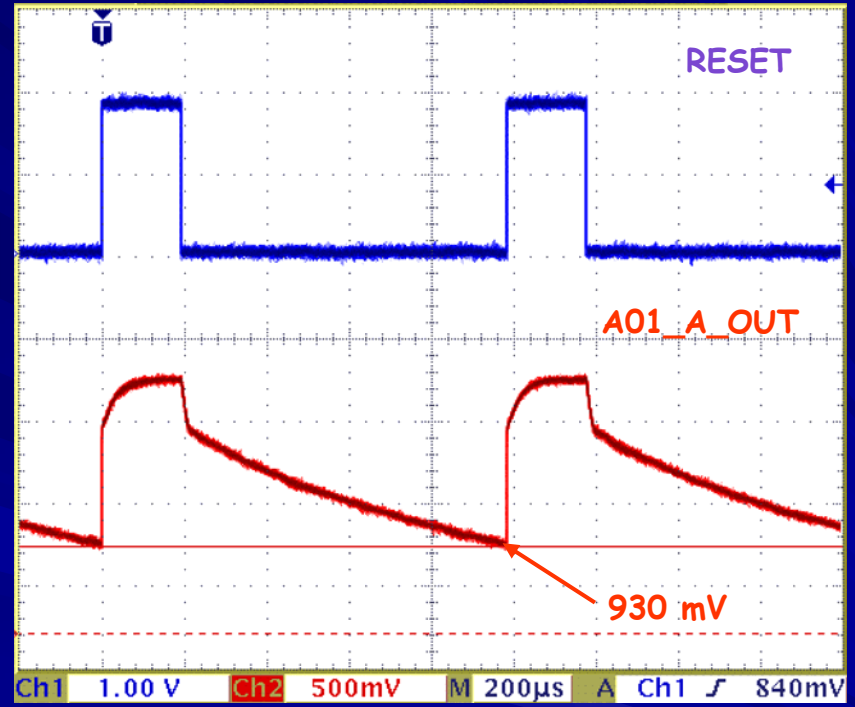


# Test results (1)

## APS preliminary results



Pixel (0,0), Array 01:  
dark condition response



Pixel (0,0), Array 01:  
light response

# *The RAPS experiment*

- **Preliminary test results on RAPS01:**
  - both pixel schemes functional
  - promising performance
- **Extensive test to be completed:**
  - statistical characterization
  - dynamic performance
  - spatial resolution
  - beam test
- **RAPS02 chip:**
  - performance tuning
  - more effective exploitation of sparse-reading features
  - on-chip signal processing



# Conclusions

- Many groups are interested in pixel development.
- Possible overlap with active pixels developed for LC applications
- The RD50 pixel subgroup is just started and we are still finding out about different activities.